

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	PRESSURE ASSISTED WAFER HOLDING APPARATUS AND CONTROL METHOD						
<p>Application Number :</p> <p>Confirmation Number:</p> <p>First Named Applicant: David Bain</p> <p>Attorney Docket Number: FIS920040119US1</p> <p>Art Unit:</p> <p>Examiner:</p> <p>Search string: (5413360 or 5522131 or 5812361 or 6084763 or 6370006 or 6414834 or 6557248 or 6581275).pn</p>							
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
LR	1	5413360	1995-05-09	Atari et al		279	128
LR	2	5522131	1996-06-04	Steger		29	829
LR	3	5812361	1998-09-22	Jones et al		361	234
LR	4	6084763	2000-07-04	Hirano et al		361	234
LR	5	6370006	2002-04-09	Kumar et al		361	234
LR	6	6414834	2002-07-02	Weldon et al		361	234
LR	7	6557248	2003-05-06	Shamouilian et al		29	825
LR	8	6581275	2003-06-24	Narendrnath et al		29	825
Signature							
Examiner Name				Date			
hegemony				03/30/06			